

Amendments to the Claims:

The following listing of claims will replace all prior versions, and listings, of claims in the application:

1. (Currently Amended) A pyrotechnic microsystem comprising a substrate having at least two separate electrical initiation zones of a pyrotechnic material deposited on the substrate for ignition by at least one initiator, characterized in that wherein the same pyrotechnic material deposit covers both initiation zones, said deposit ~~produced on the substrate~~ having a thickness sufficiently small for the initiation of the pyrotechnic material at one initiation zone to remain localized and self-extinguishing and not propagate to the other initiation zone, but sufficient to generate a specific gas quantity.

2. (Currently Amended) The microsystem as claimed in claim 1, wherein the pyrotechnic material deposit ~~is produced with~~ has a thickness of less than 100 μm .

3. (Currently Amended) The microsystem as claimed in claim 1, wherein the substrate ~~is produced from~~ comprises an assembly of superimposed layers.

4. (Previously Presented) The microsystem as claimed in claim 3, wherein the pyrotechnic material deposit constitutes one of the superimposed layers.

5. (Currently Amended) The microsystem as claimed in claim 4, wherein the pyrotechnic material deposit is ~~used as an adhesive for assembly~~ between a layer lying above said deposit and a layer lying below said deposit.

6. (Previously Presented) The microsystem as claimed in claim 1, wherein the deposited pyrotechnic material is in the form of a nitrocellulose-based varnish.

7. (Currently Amended) The microsystem as claimed in claim 6, wherein the varnish ~~is deposited with~~has a thickness of between 5 and 40 μm after drying.

8. (Currently Amended) The microsystem as claimed in claim 1, wherein each of the initiation zones can be ~~produced from~~initiated by an electrical resistance on the substrate.

9. (Currently Amended) The microsystem as claimed in claim 1, wherein each of the initiation zones can be produced at the point of contact of a conductive finger, connected to an electrical generator on the substrate, and wherein the substrate is made of metallic substance, which is also connected to said generator.

10. (Currently Amended) The microsystem as claimed in claim 3, comprising a deformable membrane partially delimiting a combustion chamber ~~intended to receive the~~ gases generated by at least one part of the pyrotechnic material deposit in contact with one of the initiation zones.

11. (Currently Amended) The microsystem as claimed in claim 10, comprising a layer through which an orifice forming the combustion chamber is formed, said layer being ~~held~~ between the membrane, itself forming a layer, and the pyrotechnic substance deposit.

12. (Currently Amended) A method for fabricating a microsystem comprising a plurality of adjacent microactuators established on a substrate, each microactuator being

capable of having a specific effect owing to the gases generated by the combustion of a pyrotechnic material initiated from an electrical initiation zone associated with each microactuator, ~~wherein the method comprising: depositing~~ a pyrotechnic material layer common to all the microactuators ~~is deposited~~ on the substrate with a thickness sufficiently small for the initiation of the pyrotechnic substance in one initiation zone to remain localized and not propagate to the other initiation zone, but sufficient to generate a specific gas quantity.

13. (Currently Amended) The method as claimed in claim 12, ~~wherein it consists only~~ inconsisting of stacking superimposed layers, the pyrotechnic material layer constituting one of the layers of the stack.

14. (Previously Presented) The method as claimed in claim 12, wherein the pyrotechnic material layer is deposited with a thickness of less than 100 μm .

15. (Currently Amended) The method as claimed in claim 12, wherein the pyrotechnic material layer is deposited by coating, screen printing, pad printing, immersion or ~~by spraying~~.

16. (New) The microsystem as claimed in claim 1, comprising at least one microactuator on said substrate.

17. (New) The microsystem as claimed in claim 16, wherein said microactuator comprises a chamber covered by a deformable membrane.

18. (New) The microsystem as claimed in claim 16, comprising a plurality of microactuators on said substrate.